

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
Thomas A. Figura, Kevin Donohoe, & Thomas Dunbar

Serial No.:

Filed: December 22, 1999

Title: USE OF A PLASMA SOURCE TO FORM A LAYER  
DURING THE FORMATION OF A SEMICONDUCTOR DEVICE

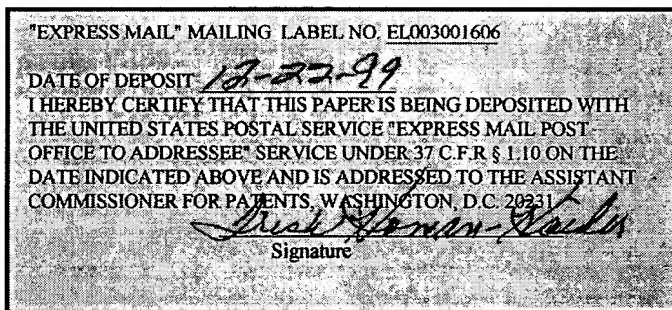
§  
§ Group Art Unit:  
§  
§ Application Examiner:  
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§ Atty. Docket: 94-0280.04  
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*Prel. Amntt*  
*# 2/A*  
*3-2-00*  
*Linda*  
*B.*

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:



After awarding this application the benefit of the filing date of the great-grandparent application, filed June 2, 1995, please amend the accompanying continuation application as follows:

IN THE SPECIFICATION

After the title, please include the following --

RELATED APPLICATIONS

This application is a divisional of a pending U.S. application, serial number 09/046,835, filed on October 24, 1997; which is a continuation of U.S. application serial number 08/787,453, filed January 22, 1997 and issued on September 7, 1999 as U.S. Patent No. 5,950,092; which is a continuation of U.S. application Serial Number 08/458,861, filed June 2, 1995 and now abandoned. --